

PATENT

1765-418 18 4/6/00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS:

HEINRICH HENNHÖFER ET AL.

SERIAL NO.:

09/032,305

EXAMINER: R. KUNEMUND

FILED:

February 27, 1998

GROUP:

1765

TITLE:

PROCESS FOR TREATING A POLISHED SEMICONDUCTOR WAFER IMMEDIATELY AFTER THE SEMICONDUCTOR WAFER

HAS BEEN POLISHED

AMENDMENT IN RESPONSE TO SECOND NON-FINAL OFFICE ACTION

ATTN: BOX NON-FEE AMENDMENT

Assistant Commissioner for Patents

Washington, D.C. 20231

Dear Sir:

In response to the Second Non-Final Office Action dated December 29, 1999, please amend the above-identified patent application as follows:

IN THE CLAIMS:

Please cancel claim 8 without prejudice, and please ? incorporate the limitations thereof into claim 1 as follows:

1. (Twice Amended) Process for treating a polished semiconductor wafer consisting essentially of the steps of polishing a surface of a semiconductor wafer; immediately after polishing the semiconductor wafer,